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APPLICATION NO	. F	TLING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.	
09/512,497 02/24/2000		02/24/2000	Daniel M. Kinzer	IR-1649(2-1939)	IR-1649(2-1939) 5663	
2352	7590	04/24/2002				
OSTROLENK FABER GERB & SOFFEN				EXAMINER		
	80 AVENUE OF THE AMERICAS EW YORK, NY 100368403			SEFER, AHMED N		
				ART UNIT	PAPER NUMBER	
				2826		
			DATE MAILED: 04/24/2002			

Please find below and/or attached an Office communication concerning this application or proceeding.

				11			
		Application No.	Applicant(s)	,			
	08: 4-4: 0	09/512,497	KINZER ET AL.				
	Office Action Summary	Examiner	Art Unit				
		A. Sefer	2826				
Period fo	The MAILING DATE of this communication apports. The MAILING DATE of this communication apports	pears on the cover sheet with the o	correspondence address				
THE - External control	ORTENED STATUTORY PERIOD FOR REPL MAILING DATE OF THIS COMMUNICATION. Insions of time may be available under the provisions of 37 CFR 1.1 SIX (6) MONTHS from the mailing date of this communication. The period for reply specified above is less than thirty (30) days, a reploperiod for reply is specified above, the maximum statutory period to reply within the set or extended period for reply will, by statute reply received by the Office later than three months after the mailing ed patent term adjustment. See 37 CFR 1.704(b).	36(a). In no event, however, may a reply be ting within the statutory minimum of thirty (30) day will apply and will expire SIX (6) MONTHS from a cause the application to become ABANDONE	nety filed s will be considered timely. the mailing date of this communication. D (35 U.S.C. § 133).				
1)	Responsive to communication(s) filed on	·					
2a)[☐	This action is FINAL . 2b)⊠ Th	nis action is non-final.					
3) 🗌	Since this application is in condition for allow closed in accordance with the practice under						
<u> </u>	ion of Claims						
4)[X]	Claim(s) <u>1-21</u> is/are pending in the application						
E)[]	4a) Of the above claim(s) <u>21</u> is/are withdrawn from consideration.						
	Claim(s) is/are allowed.						
	Claim(s) <u>1-20</u> is/are rejected.						
	Claim(s) is/are objected to.	. 1. 6					
	Claim(s) are subject to restriction and/o ion Papers	or election requirement.					
	The specification is objected to by the Examine	ar.					
·	The drawing(s) filed on is/are: a)☐ acce		miner				
. •/	Applicant may not request that any objection to th						
11)[]	The proposed drawing correction filed on						
, —	If approved, corrected drawings are required in re		•				
12)	The oath or declaration is objected to by the Ex	caminer.					
Priority (under 35 U.S.C. §§ 119 and 120						
13)	Acknowledgment is made of a claim for foreign	n priority under 35 U.S.C. § 119(a	a)-(d) or (f).				
a)	☐ All b)☐ Some * c)☐ None of:						
	1. Certified copies of the priority document	s have been received.					
	2. Certified copies of the priority document	s have been received in Applicati	ion No				
* 5	Copies of the certified copies of the prio application from the International Buse the attached detailed Office action for a list	reau (PCT Rule 17.2(a)).					
	Acknowledgment is made of a claim for domesti	·					
a	The translation of the foreign language pro Acknowledgment is made of a claim for domest	ovisional application has been rec	eived.				
Attachmen	·						
1) 🔯 Notic 2) 🔲 Notic	ce of References Cited (PTO-892) se of Draftsperson's Patent Drawing Review (PTO-948) mation Disclosure Statement(s) (PTO-1449) Paper No(s) _	5) Notice of Informal	y (PTO-413) Paper No(s) Patent Application (PTO-152)				

DETAILED ACTION

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Claim Rejections - 35 USC § 103

- 1. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
 - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.
- 2. Claims 1-12 are rejected under 35 U.S.C. 103(a) as being unpatentable over Baba et al. US Patent No. 5,321,289 in view of Kim US Patent No. 5,574,299.

Baba et al disclose in fig. 1B a Mosgated device comprising a semiconductor substrate 10 of N+ conductivity and having an upper planar surface; a channel diffusion region 12 of P conductivity which extends into said upper planar surface of said substrate and to a first depth below said surface; a source diffusion 13 of N+ conductivity which extends into said substrate to a second depth which is less than the first depth; a plurality of spaced trenches 14 formed into said substrate and into its said planar surface to a third depth below said substrate surface which is greater than said first depth; an insulation gate layer 15 formed on the walls of said plurality of trenches at least in the areas between said first and second depths; conductive gate bodies disposed within the interiors of each of said trenches; a source contact S connected to said source diffusion region at a location on said upper planar surface which is completely laterally removed from said plurality of trenches; a drain contact D connected to said substrate.

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Kim discloses in figs. 23 and 25 a plurality of narrow, spaced conductive gate strips 132 disposed atop an insulation gate layer 130 and extending across and contacting conductive bodies.

Therefore, it would have been obvious to one skilled in the art at the time the invention was made to incorporate Kim's teachings with Baba et al, since that would prevent a snapback.

As for claim 2, Baba et al disclose in fig. 1A a plurality of spaced trenches which are parallel to one another and are coextensive with one another.

As for claim 3, Baba et al disclose in fig. 1A a plurality of spaced trenches formed in a plurality of spaced rows and are parallel to one another and are coextensive with one another within each row.

As to claim 10, Baba el disclose (see col. 2, lines 35-39) an oxide gate insulation layer fully covering the interior of each said trenches and wherein each said conductive bodies is polysilicon which completely fills each of said trench and is insulated from said substrate, but does not specifically disclose a thickness range of the insulation layer. However, it would have been obvious to use a thickness range of about 200 Å, since the described limitation would have been considered an optimization or workable range involving a routine skill in the art.

As to claim 11, Baba et al disclose in fig. 1B a source contact connected to a channel region and to a source region.

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As to claims 4-9, the specification contains no disclosure of either the critical nature of the claimed arrangement or any unexpected results arising therefrom. Where patentability is said to be based upon particular chosen dimensions or upon another variable recited in a claim, the applicant must show that the chosen dimensions are critical. In re Woodruff, 919 F.2d 1575, 1578, 16 USPQ2d 1934, 1936 (Fed. Cir. 1990).

As to claim 12, Baba et al disclose in fig. 1B Baba et al disclose in fig. 1B a Mosgated device comprising a semiconductor substrate 10 of N+ conductivity and having an upper surface; at least first and second invertible vertical channel forming trenches 14 formed through said upper surface and into said substrate for a first depth; a gate oxide 15 coating the interior walls of said at least first and second trenches; channel region 12 of P conductivity disposed adjacent to a portion of the length of the walls of said first and second trenches and to a second depth below said upper surface, said second depth being less than said first depth; a shallow source 13 which extends from said upper surface and into said substrate for a third depth; said third depth being less than said second depth; first and second polysilicon layers G filling said at least first and second trenches respectively and which are insulated from said substrate.

Kim discloses in figs. 23 and 25 a plurality of narrow, spaced conductive gate strips 132 disposed atop an insulation gate layer 130 and extending across and contacting conductive bodies.

Therefore, it would have been obvious to one skilled in the art at the time the invention was made to incorporate Kim's teachings with Baba et al, since that would prevent a snapback.

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4. Claims 13-20 are rejected under 35 U.S.C. 103(a) as being unpatentable over

Baba et al in view of Huang US Patent No. 6,110,799.

Baba et al disclose all the claimed subject matter including a source contact S

which is fully laterally spaced from an upper surface which is connected to a source

region 13 at a location remote from first and second trenches 14, but does not

specifically disclose the location of said source contact.

However, Huang discloses in fig. 9, a source contact 36 located between first

and second trenches. Therefore, it would have been obvious to locate a source contact

between two trenches, since that would maximize its contact.

As to claims 14 and 20, Baba et al disclose a source contact connected to a

channel region at said remote location.

As to claims 15-19, the specification contains no disclosure of either the critical

nature of the claimed arrangement or any unexpected results arising therefrom. Where

patentability is said to be based upon particular chosen dimensions or upon another

variable recited in a claim, the applicant must show that the chosen dimensions are

critical. In re Woodruff, 919 F.2d 1575, 1578, 16 USPQ2d 1934, 1936 (Fed. Cir. 1990).

Any inquiry concerning this communication or earlier communications from the

examiner should be directed to A. Sefer whose telephone number is (703) 605-1227.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's

supervisor, Nathan J Flynn can be reached on (703) 308-6601.

ANS April 22, 2002 NATHAN J. FLYNN SUPERVISORY PATENT EXAMINER TECHNOLOGY CENTER 2800